

**Amendments to the Specification**

Please replace the paragraph beginning on page 3, line 29, with the following:

-- FIG. 1A illustrates a high-level block diagram of a laser thermal (LT) printer system; --

Please replace the paragraph beginning on page 4, line 1, with the following:

-- FIGS. ~~1A and 1B~~ 1B and 1C illustrate a side view and top view, respectively, of the laser thermal (LT) printer system of FIG. 1 for use in an OLED fabrication process; --

Please replace the paragraph beginning on page 5, line 9, with the following:

-- FIG. 1A illustrates a high-level block diagram of laser thermal (LT) printer system 100 for use in an OLED fabrication process. LT printer system 100 includes a vacuum chamber 122, a controller 111, a motion control system 110 upon which is mounted a laser thermal (LT) station 112, and a detection system 114. Laser light beams can be directed to either the vacuum chamber 122 or the detection system 114 depending upon the positional commands 113 sent to the motion control system 110, and further depending upon the printhead control commands 115 sent by the controller 111 to the LT station 112. In response to the receipt of laser light beams directed to the correct portion of detection system 114, and upon commands from the controller 111, the detection system 114 will return irradiance data 117 to the controller 111. During the gathering of irradiance data 117, the controller 111 also gathers positional data 119 from the motion control system 110. --

Please replace the paragraph beginning on page 5, line 22, with the following:

-- FIGS. ~~1A and 1B~~ 1B and 1C illustrate a more detailed side view and top view, respectively, of portions of laser thermal (LT) printer system 100 including the motion control system 110 upon which is mounted an LT station 112 and a detection system 114. --

Please replace the paragraph beginning on page 6, line 31, with the following:

-- A narrow aperture of uniform gap, sometimes referred to as a slit aperture, is shown as X-slit aperture 130 in FIG. ~~1B~~ 1C, and another is shown

as Y-slit aperture **134**. These are custom aperture devices that have narrow openings (i.e., slit **132** and slit **136**, respectively) through which light passes. Slit **132** and slit **136** are oriented orthogonal to one another, as shown in FIG. **4B\_1C**. X-photodetector **138** and Y-photodetector **140** are conventional optical sensors, such as United Detector Technology PIN 6DI, for detecting the laser light wavelength band. --